## **WEST Search History**

Hide Items	Restore	Clear	Cancel

DATE: Monday, February 05, 2007

Hide?	<u>Set</u> Name	Query	<u>Hit</u> Count
	DB=I	PGPB, USPT, USOC; PLUR = YES; OP = ADJ	
	L14	L13 and l12	9
	L13	134/94.1,95.1,95.3,137,140,902.ccls.	3987
	L12	(substrate or semiconductor or wafer or workpiece or article) same ((hold\$3 or support\$3) with rotat\$3) same ((scatter\$4 or spatter\$4) with (cup or chamber) with (clean\$3 or rins\$3 or wash\$3))	40
	DB=I	EPAB,JPAB,DWPI; PLUR=YES; OP=ADJ	
	L11	(substrate or semiconductor or wafer or workpiece or article) same ((hold\$3 or support\$3) with rotat\$3) same ((scatter\$4 or spatter\$4) with (cup or chamber) with (clean\$3 or rins\$3 or wash\$3))	5
	DB=I	PGPB, USPT, USOC, EPAB, JPAB, DWPI; PLUR=YES; OP=ADJ	
	L10	(substrate or semiconductor or wafer or workpiece or article) same ((hold\$3 or support\$3) with rotat\$3) same ((scatter\$4 or spatter\$4) with (cup or chamber) with (clean\$3 or rins\$3 or wash\$3))	45
	L9	L8 and ((substrate or semiconductor or wafer or workpiece or article) same ((hold\$3 or support\$3) with rotat\$3)same (scatter\$3 with (cup or chamber)))	14
	L8	L7 or 16 or 15 or 14 or 13 or 12	2081
	L7	(ebara corporation).as.	1267
	Ĺ6	takeda-sachiko\$.in.	37
	L5	inoue-yuki\$.in.	685
	L4	ono-haruko\$.in.	18
	L3	katakabe-ichiro\$.in.	. 76
	L2	kajita-shinji\$.in.	35
	DB = 0	USPT; PLUR=YES; OP=ADJ	•
	L1	6265328.pn. or 6413436.pn.	2

END OF SEARCH HISTORY

## **WEST Search History**

Hide Items	Restore	Clear	Cancel

DATE: Monday, February 05, 2007

Hide?	<u>Set</u> Name	Query
	DB =	USPT; PLUR=YES; OP=ADJ
	L18	L16 and 14
	L17	L16 and 12
	L16	(chamber or cup or bowl) same ((support\$3 or hold\$3) with rotat\$4) same ((clean\$3 or ring (back or bottom or second or opposit) with (nozzle or spray\$3))
	DB =	EPAB,JPAB,DWPI; PLUR=YES; OP=ADJ
. 🗆	L15	(chamber or cup or bowl) same ((support\$3 or hold\$3) with rotat\$4) same ((clean\$3 or rins (back or bottom or second or opposit) with (nozzle or spray\$3))
	L14	(chamber or cup) same ((support\$3 or hold\$3) with rotat\$4) same ((clean\$3 or rins\$3 or w. bottom or second) with (nozzle or spray\$3))
	L13	(chamber or cup) same ((support\$3 or hold\$3) with rotat\$4) same ((clean\$3 or rins\$3 or w. bottom or second))
	DB =	JPAB; PLUR=YES; OP=ADJ
	L12	06106126
	L11	6106126
	DB =	EPAB,JPAB,DWPI; PLUR=YES; OP=ADJ
	L10	((chamber or cup) adj5 nozzle) same ((support\$3 or hold\$3) with rotat\$4) same (clean\$3 o
	L9	((chamber or cup) with nozzle) same ((support\$3 or hold\$3) with rotat\$4) same (clean\$3 o
	L8	(chamber or cup) same nozzle same ((support\$3 or hold\$3) with rotat\$4) same (clean\$3 or
	DB =	PGPB, USPT, USOC; PLUR = YES; OP = ADJ
	L7	L6 and 14
	L6	(chamber or cup) same nozzle same ((support\$3 or hold\$3) with rotat\$4) same (clean\$3 or
	L5	L4 and l1
	L4	134/104.1;118/70.ccls.
	L3	L2 and l1
	L2	134/94.1, 95.1, 95.3, 99.1, 103.2, 104.1, 137, 140, 151, 198, 199, 902, 22.1, 22.18, 34, 36; 118/52, 70
	DB =	USPT; PLUR=YES; OP=ADJ
	L1	((chamber or cup) with nozzle) same ((support\$3 or hold\$3) with rotat\$4) same (clean\$3 o

END OF SEARCH HISTORY